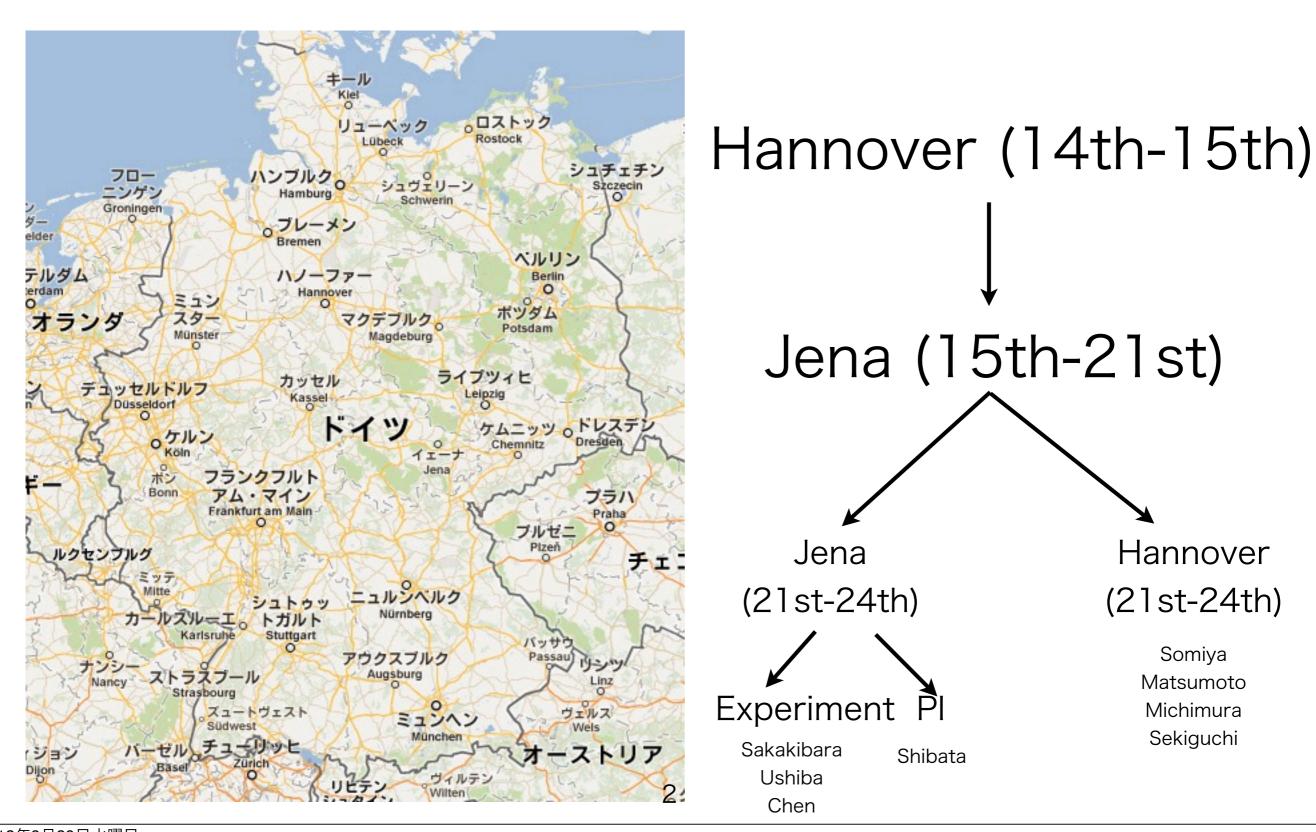
ELiTES work shop @Germany -Optical experiment-

29th/Aug/2012 Dan Chen

Schedule



Time table

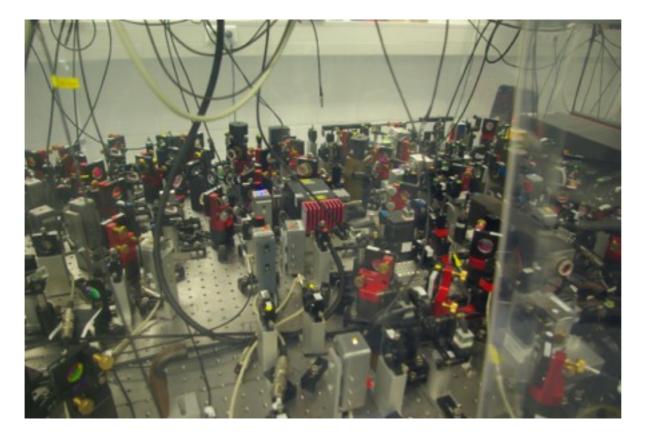
	2012/8/14	2012/8/15	2012/8/16	2012/8/17	2012/8/20	2012/8/21	2012/8/22-24
9:00-10:30		move from Hannover to Jena	thermal noise lecture (D.Heinert) 10AM	TN lecture continues	bulk loss lecture (G.Hofmann) 10AM	absorption (Komma, Steinlechner)	-
10:45-12:15				cooling time reduction (Sakakibara)		suspension (Sekiguchi)	
12:15-14:00	lab tour at Hannover	arrival & lunch	lunch				lab work
14:00-15:30	•	lab tour & informal meeting	parametric instability (Shibata)	silicon cavity (Ushiba)	coating loss (Nawrodt)	free discussion	
15:45-17:15			thermal lensing (Michimura)	120K Silicon (Somiya)	future topic (Matsumoto)		

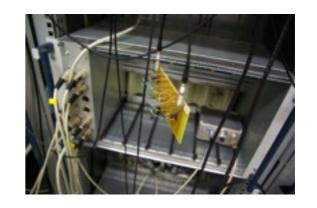
Lab tour at Hannover

10m

- seismic isolation system
- laser source

squeezer





GE0600

- Observing
- Suspension system
- control room





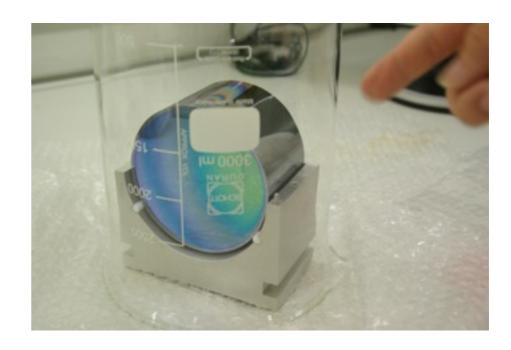




Lab tour at Jena



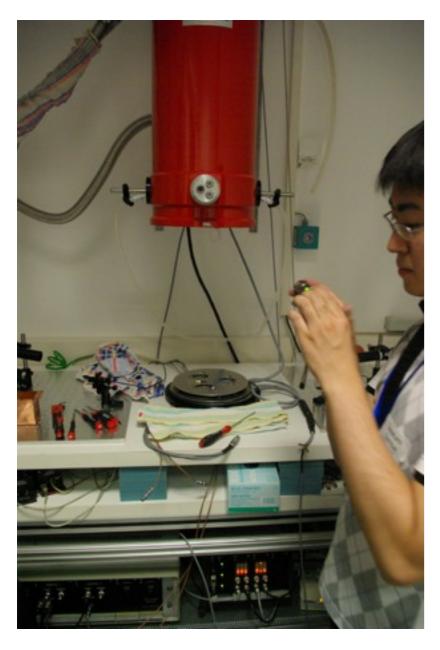
Main Lab
Measurement of the absorption of Si
Using LN_2, LHe to cool cryostat till 5K



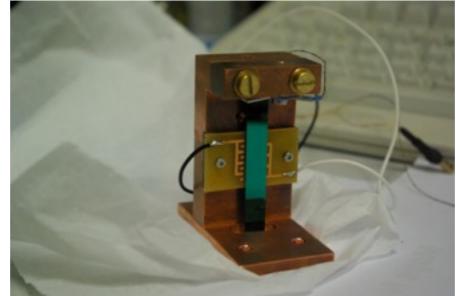
Si bulk with coating on the both of the face to construct a cavity.

Insert laser to measure the absorption of the bulk

Lab tour at Jena

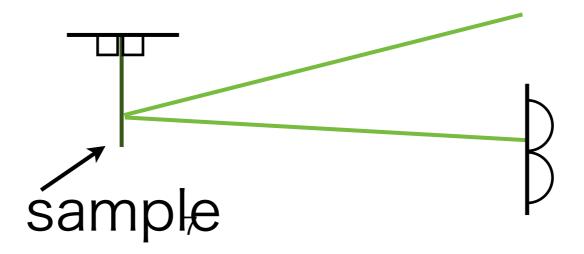


Small lab 1

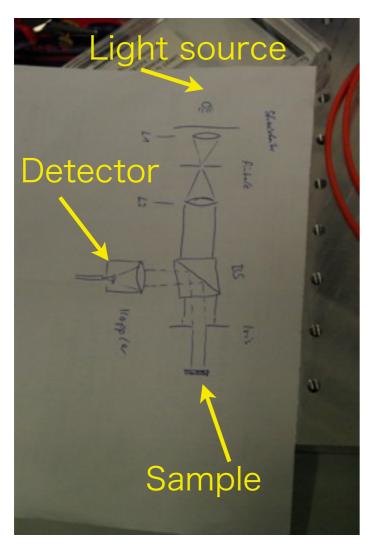


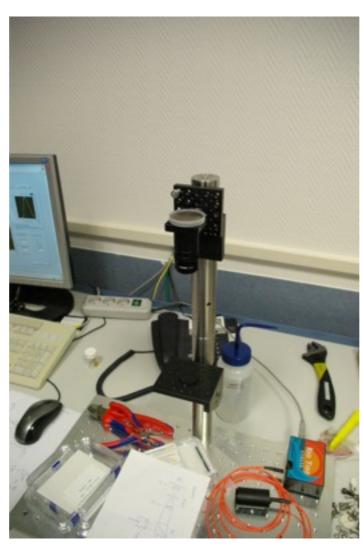


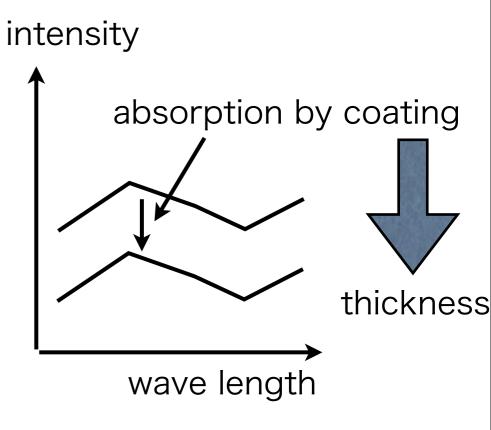
Measurement of the mechanical Q factor of the cantilever



Lab tour at Jena Small lab 1



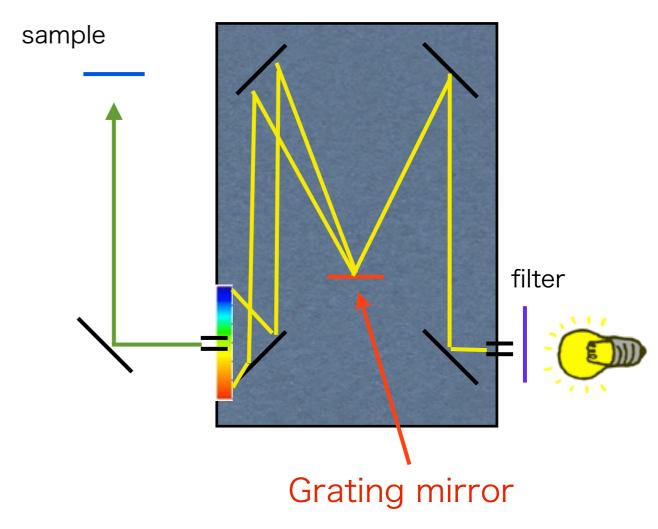




Measurement of the thickness of the coating using reflecting

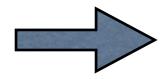
Lab tour at Jena





Small lab 2

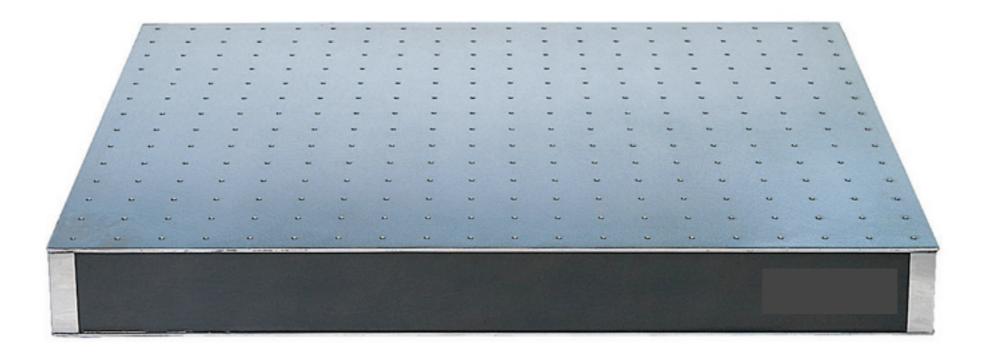
Spectroscope: Creating continuance light source to measure the absorption of the bulk.



They can use this to measure the absorption by many wave length without many light source.

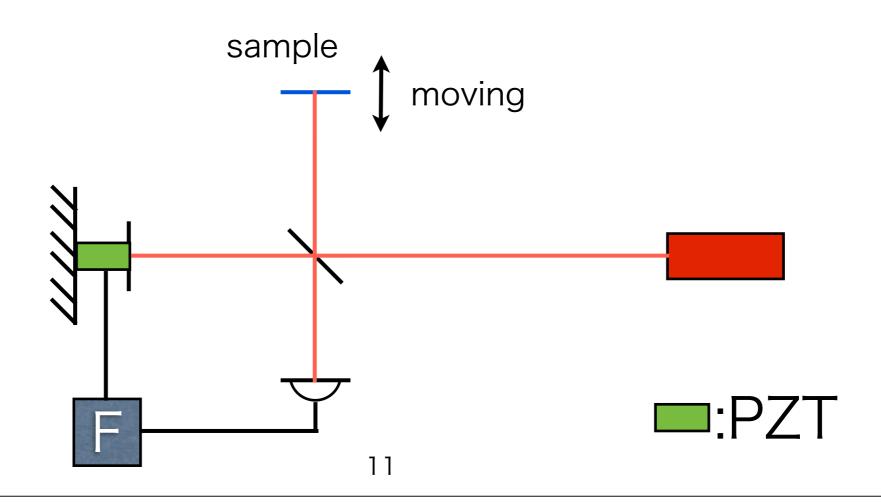
Lab work

Task: lock a Michelson interferometer by 3 days



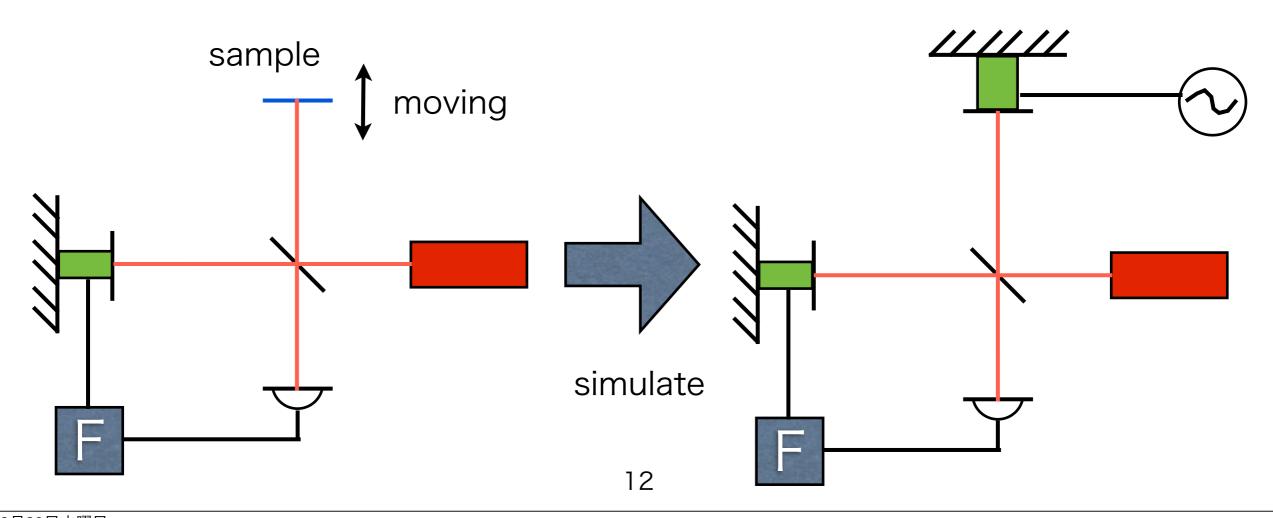
Purpose

They want to measure the mechanical Q factor of the cantilever using a Michelson interferometer.



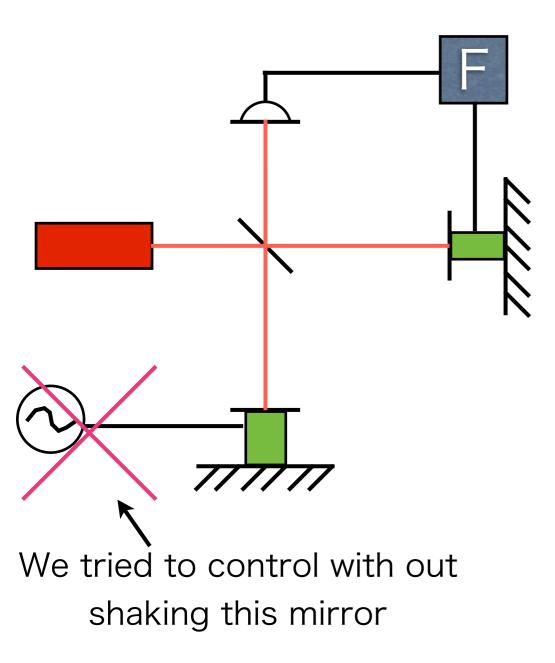
Purpose

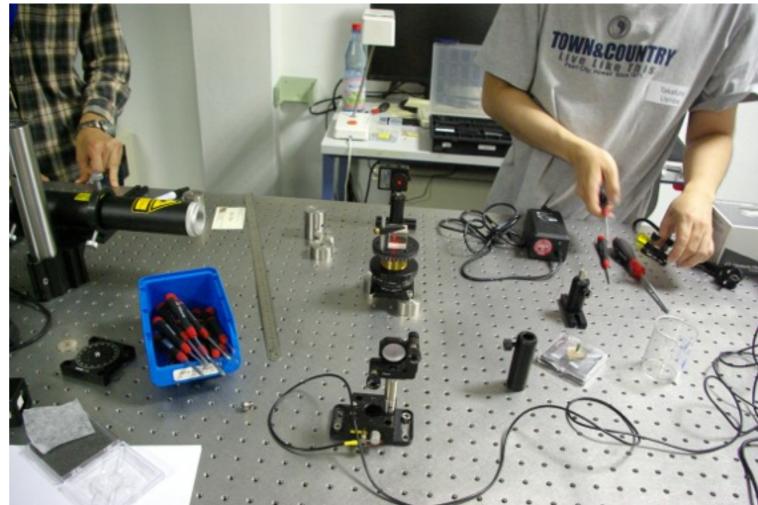
They want to measure the mechanical Q factor of the cantilever using a Michelson interferometer.



1st day

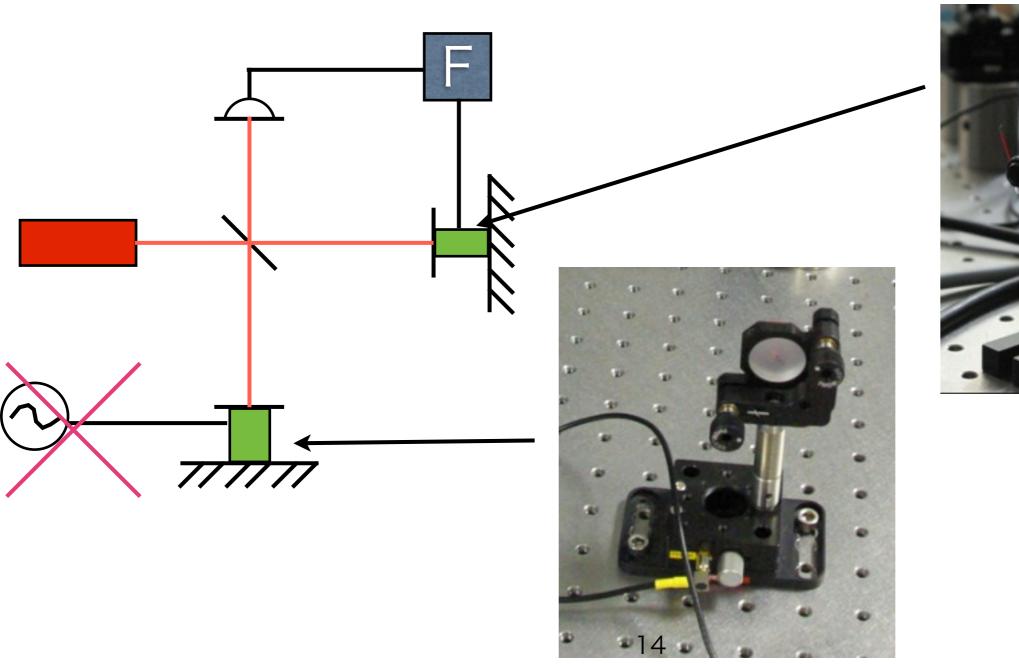
We constructed a MI which we wanted to lock at last.

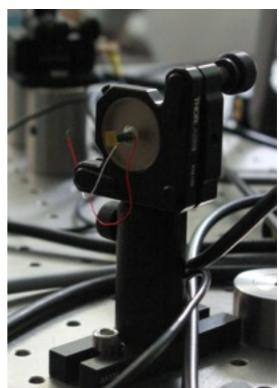




1st day

We constructed a MI which we wanted to lock at last.





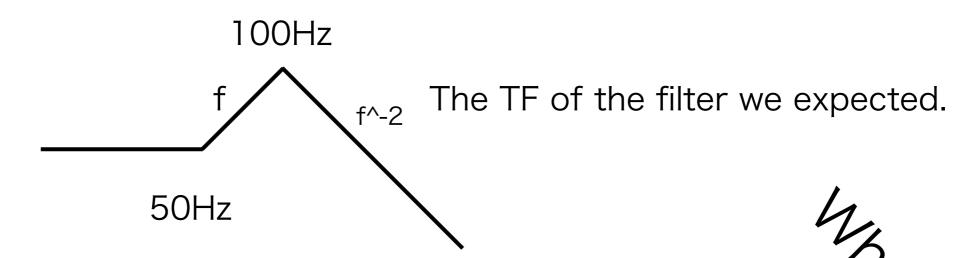
1st day

Laser source

Coherent length: 100km -> several cm

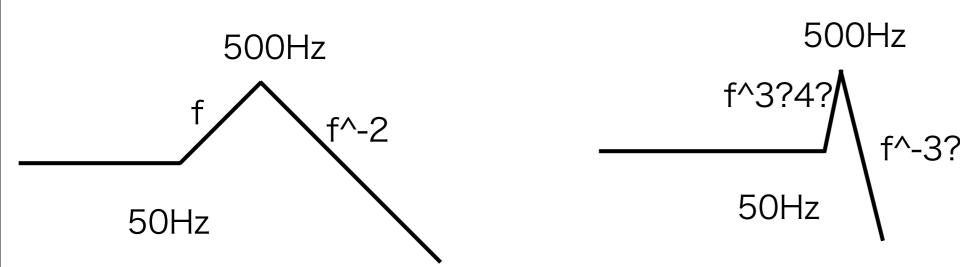
Filter

We made a control filter by SR560 and SR650



We could not control the MI.

Because the filter was not such shape. (And ...)



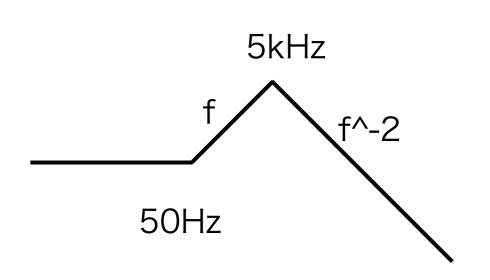
The TF of the filter we expected.

The TF of filter we measured

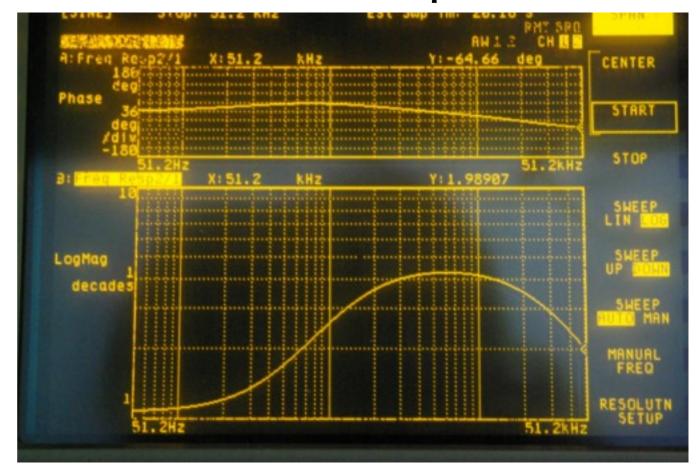
The slope was too steep.



We made a filter with OP amp.

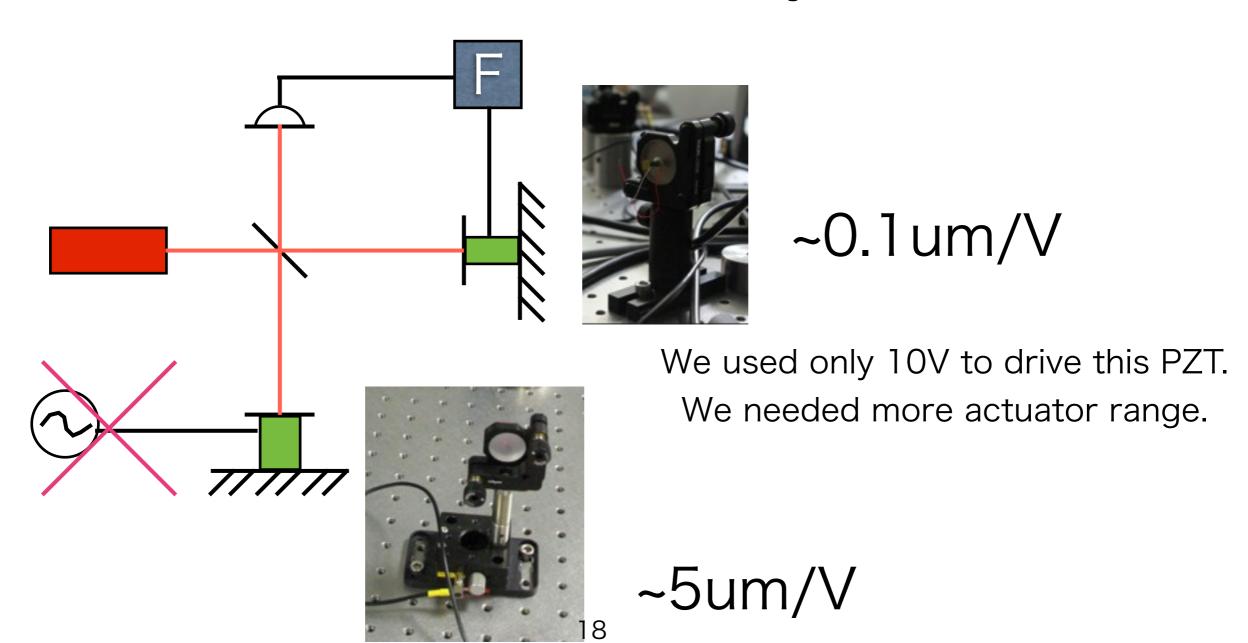


The TF of the filter we expected.

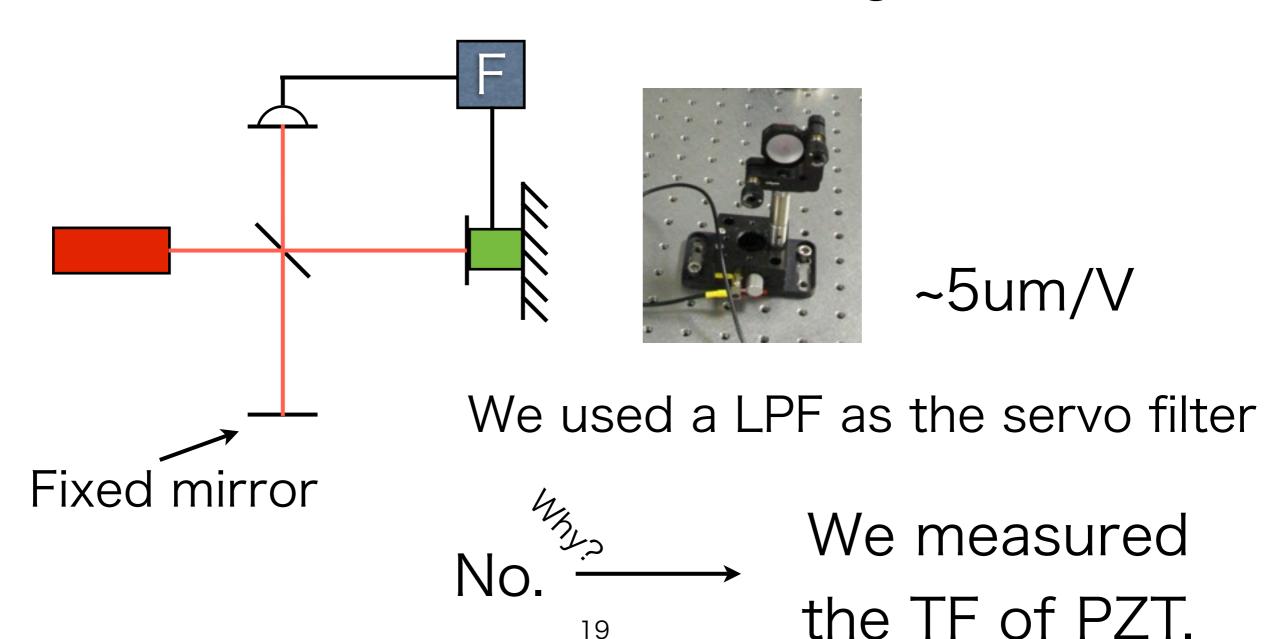


We could not control the MI.

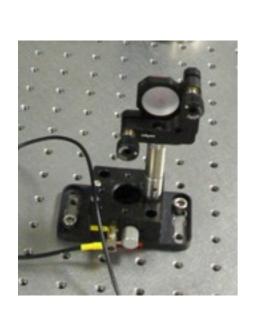
We measured the efficiency of the PZT.

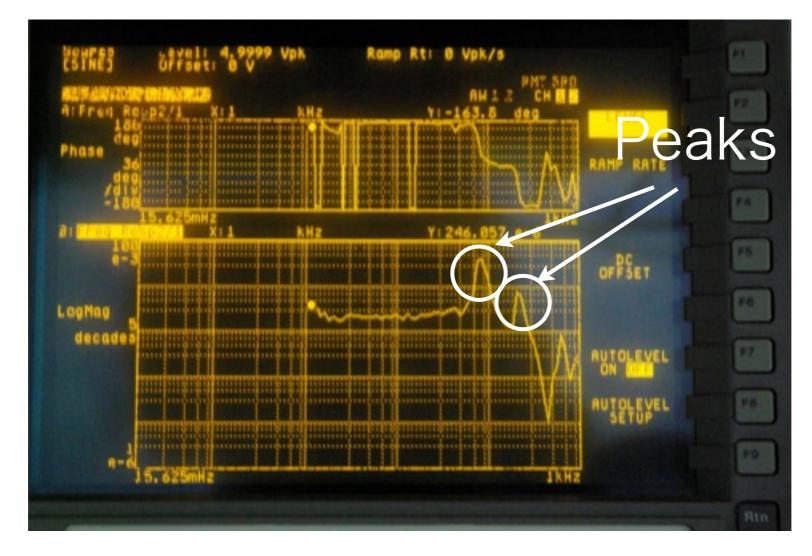


We tried to use the PZT with stage to control.



We measured the TF of PEZ.



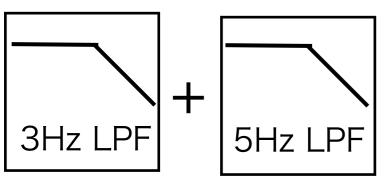


This peaks may disturb the control.

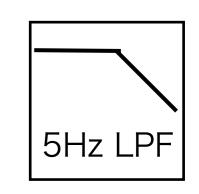
We used two LPFs to control the MI.

Experiment



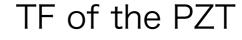


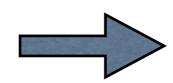




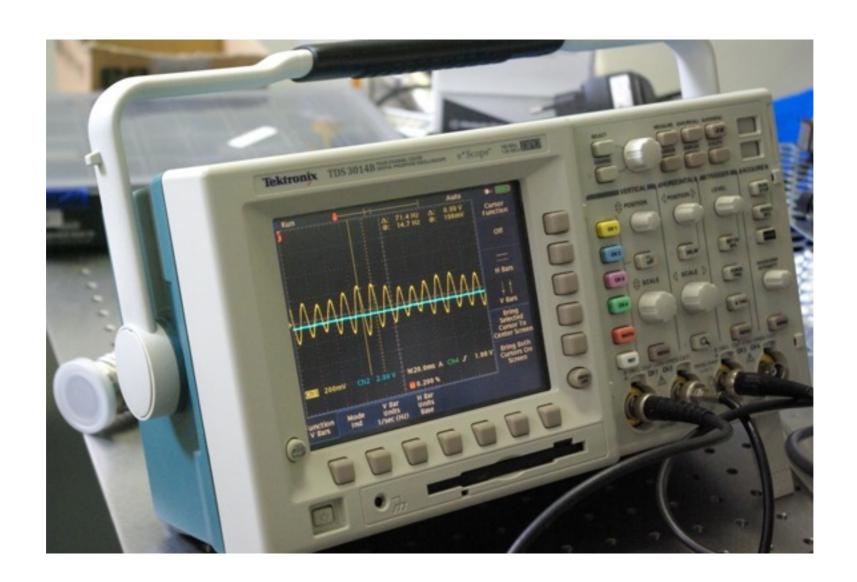








We could not suppress the peak with one LPF

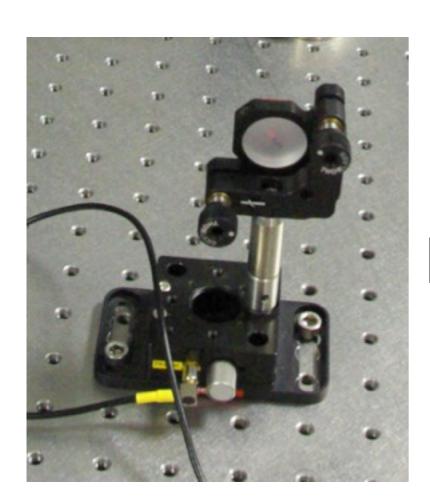


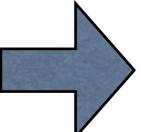
There is a peak at 70Hz.

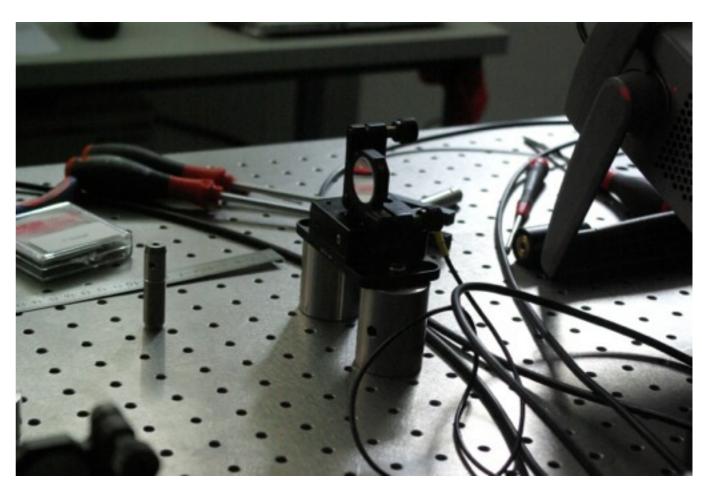


The open loop TF of the control system

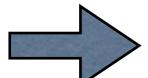
We refined the PZT.



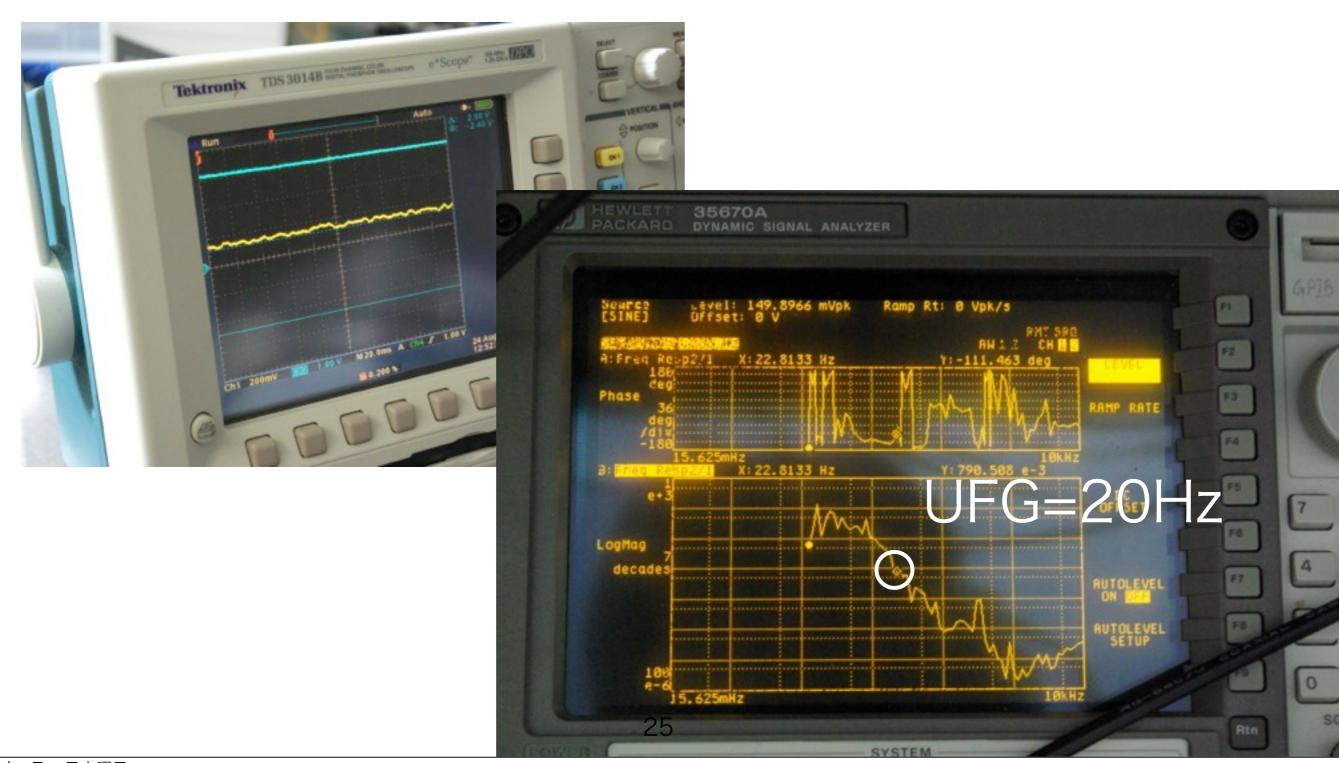




This change let the peak rise.



We could₂ raise the UGF.



 $+\alpha$

Ronny gave us high voltage amp.

We measured the TF of the small PZT.

And we found there is no peak under 10kHz



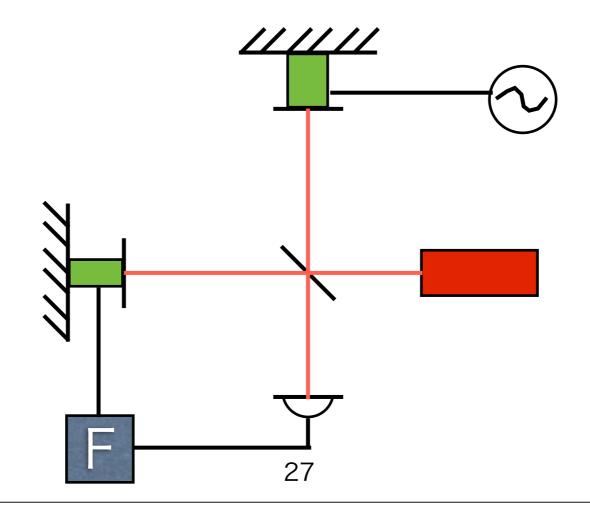


We should be able to control the MI with a high voltage amp.

(The high voltage amp Ronny gave could not be drive in low frequency.)

Future

- 1. Use a high voltage amp to lock the MI.
- 2. Change the laser source to 1550nm.
- 3. Measure the vibration of the sample.



Summery

We locked a Ml.

Problems:

- 1. The coherence length of the laser.
- 2. We should not use SR650 to make a filter.
- 3. The PZT stage had peaks to disturb control.
- 4. The small PZT need more high voltage.



